

6536025 • 6536102

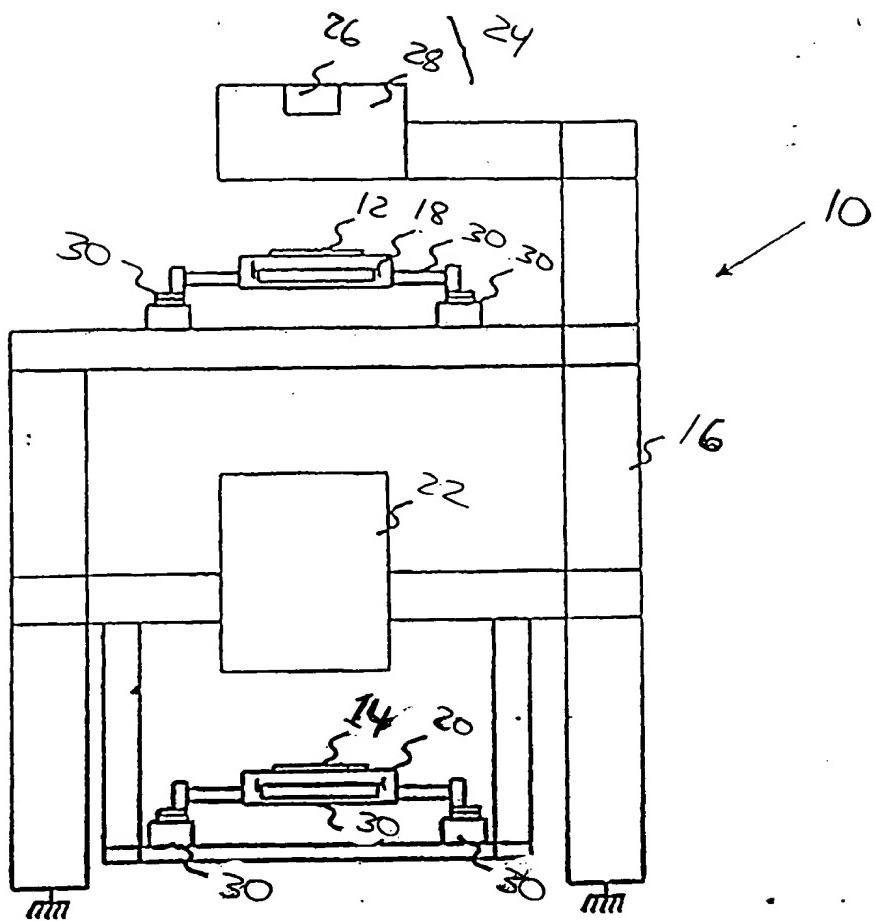
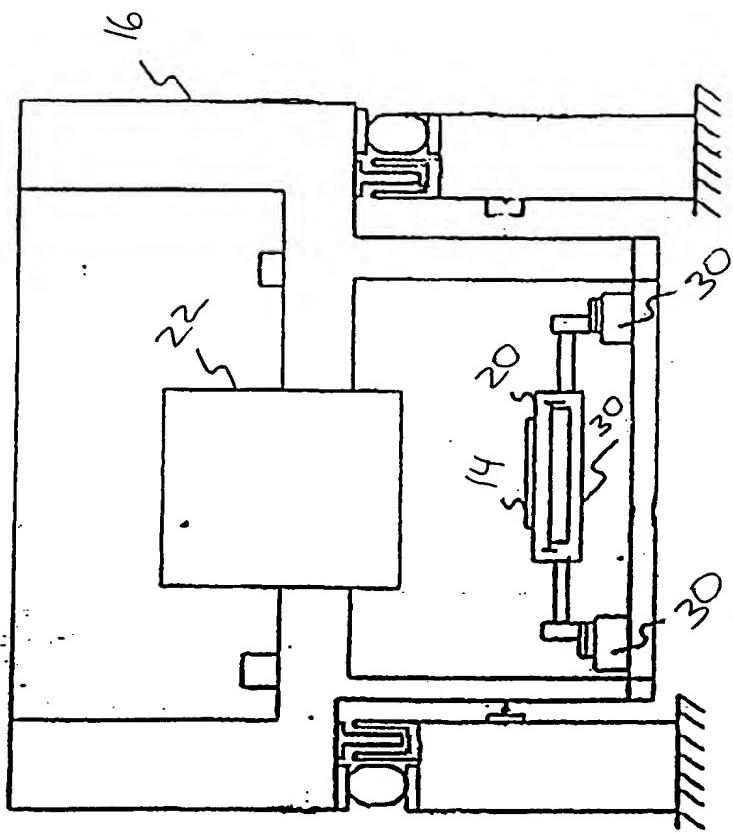


FIG. 1
Prior Art

FIG.2
Prior Art



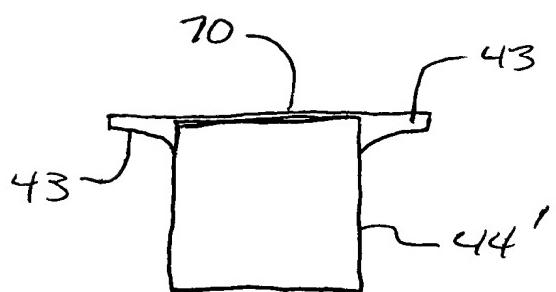
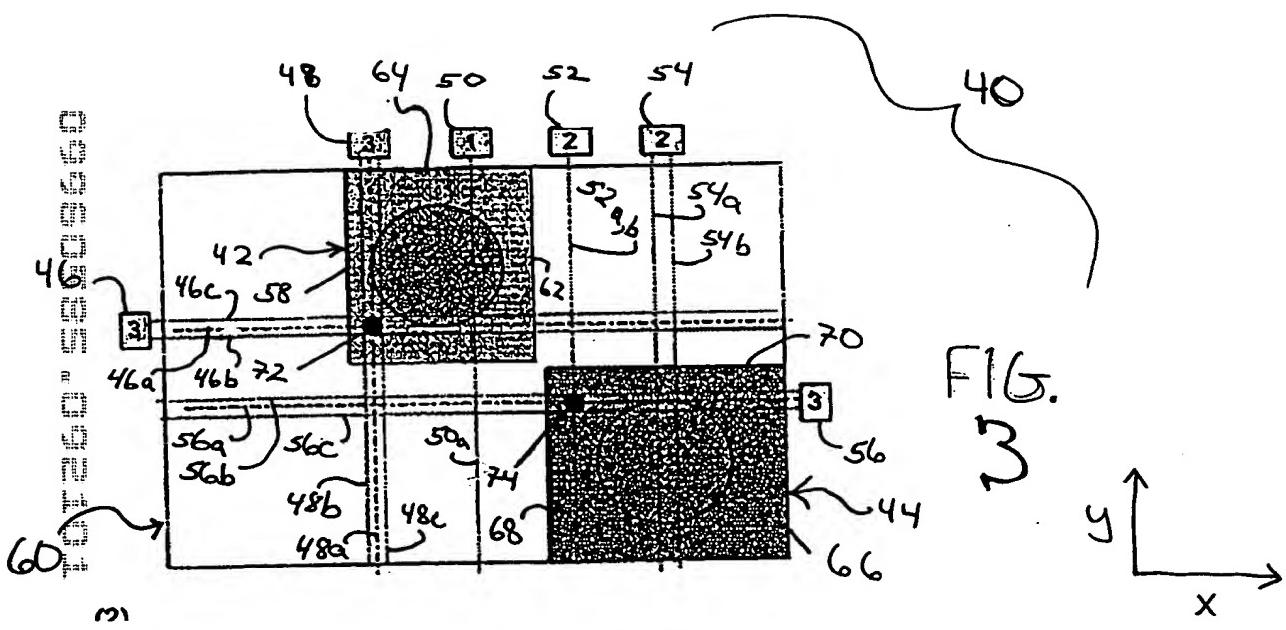


FIG. 3a

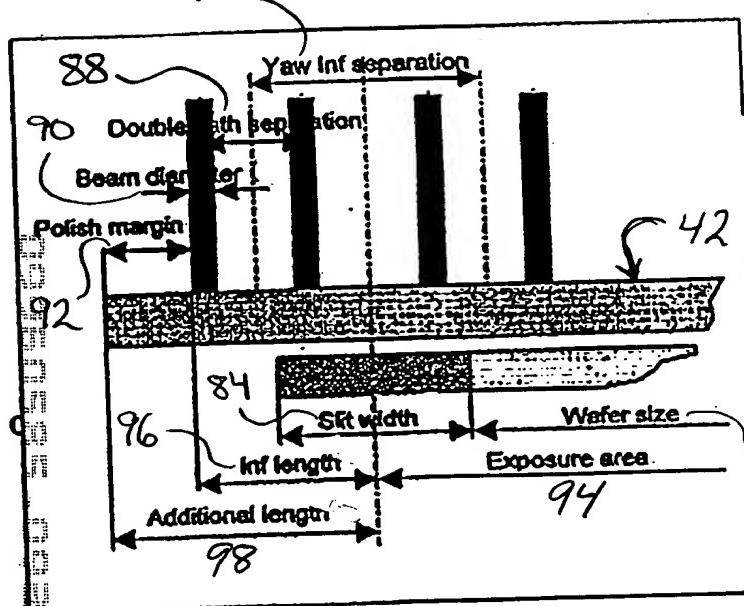


FIG. 4b

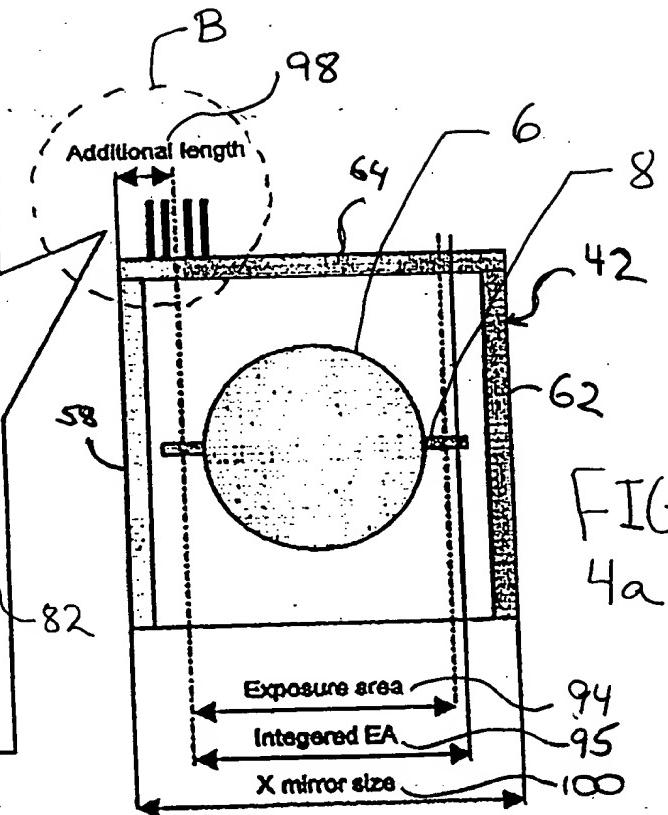


FIG.
4a

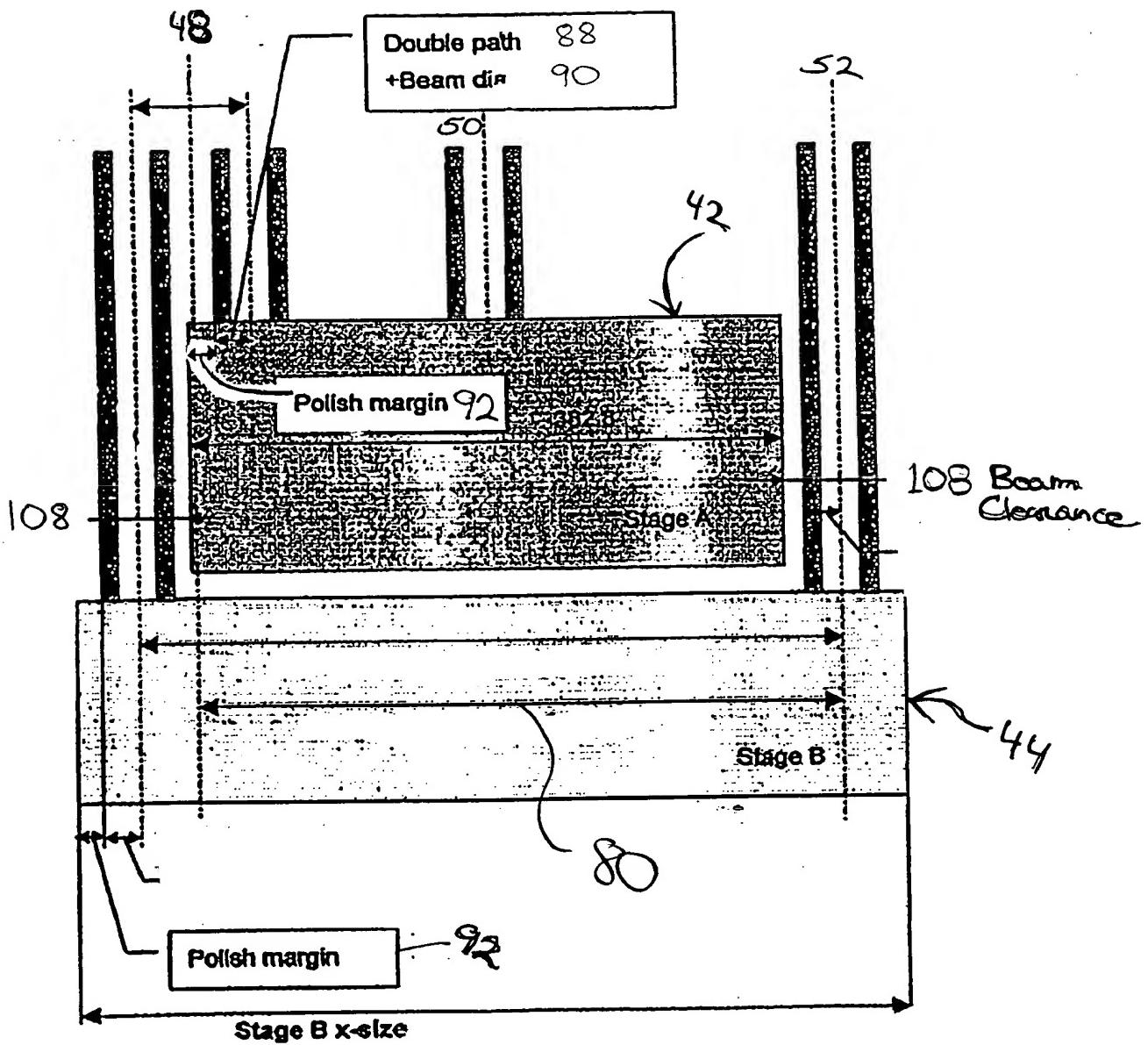
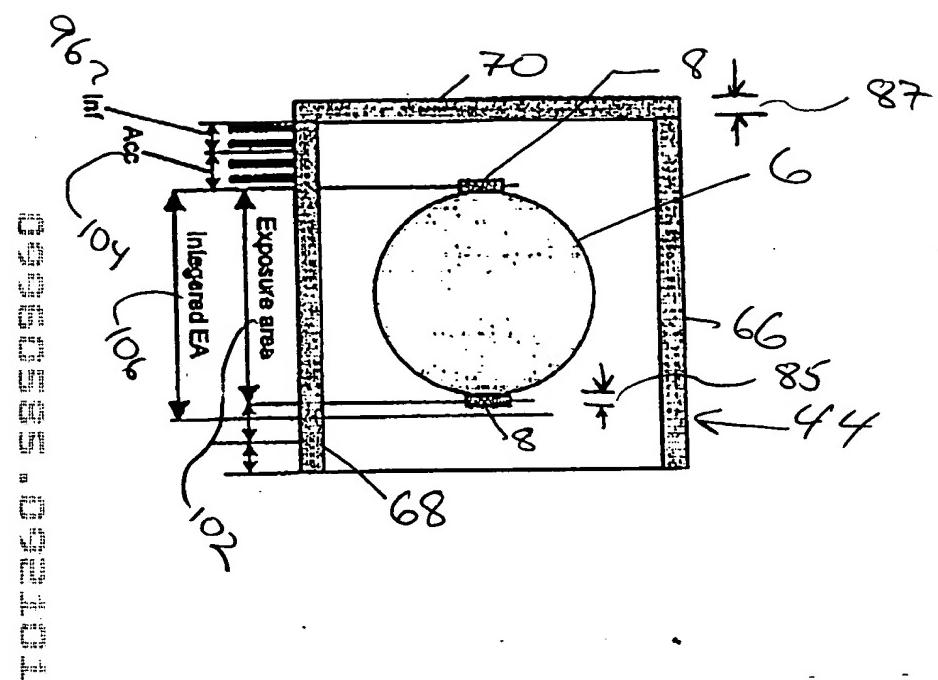


FIG. 5

FIG. 6



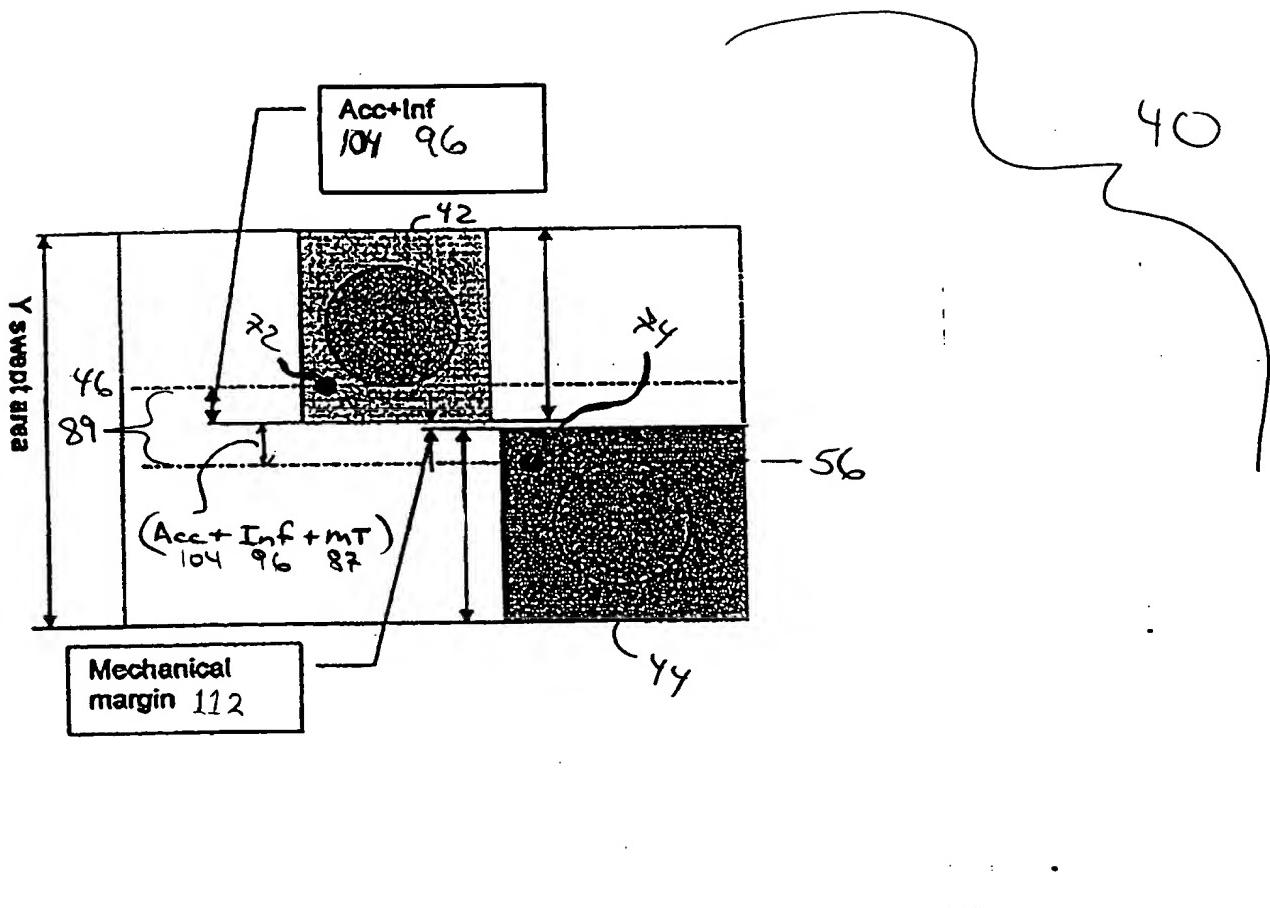


FIG. 7

09060588 092408

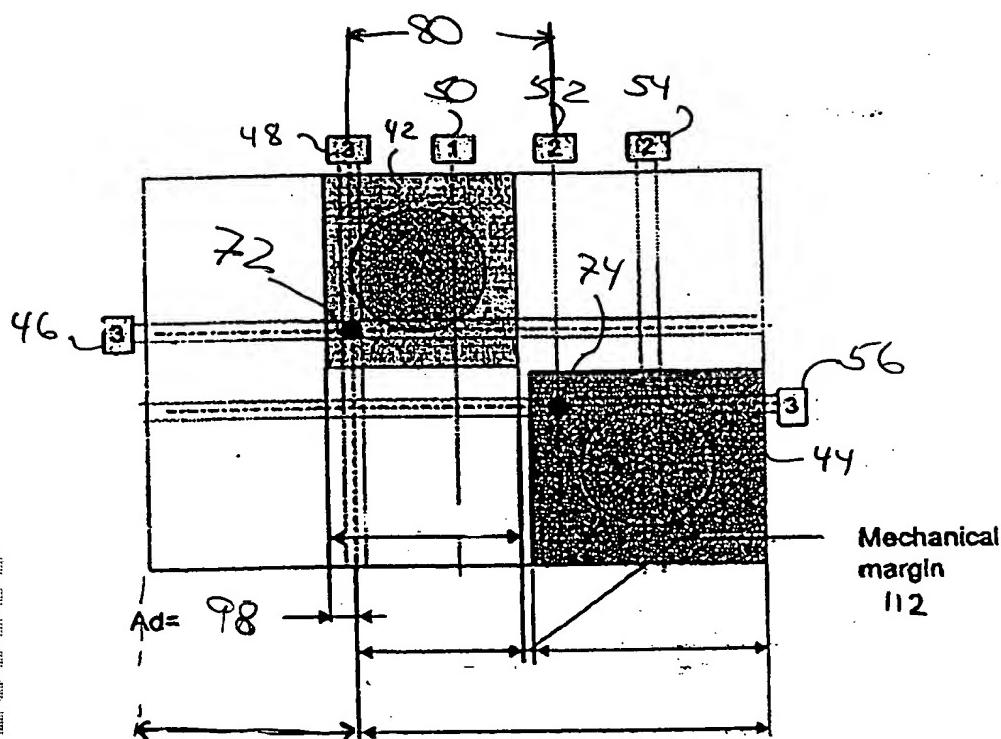


FIG. 8

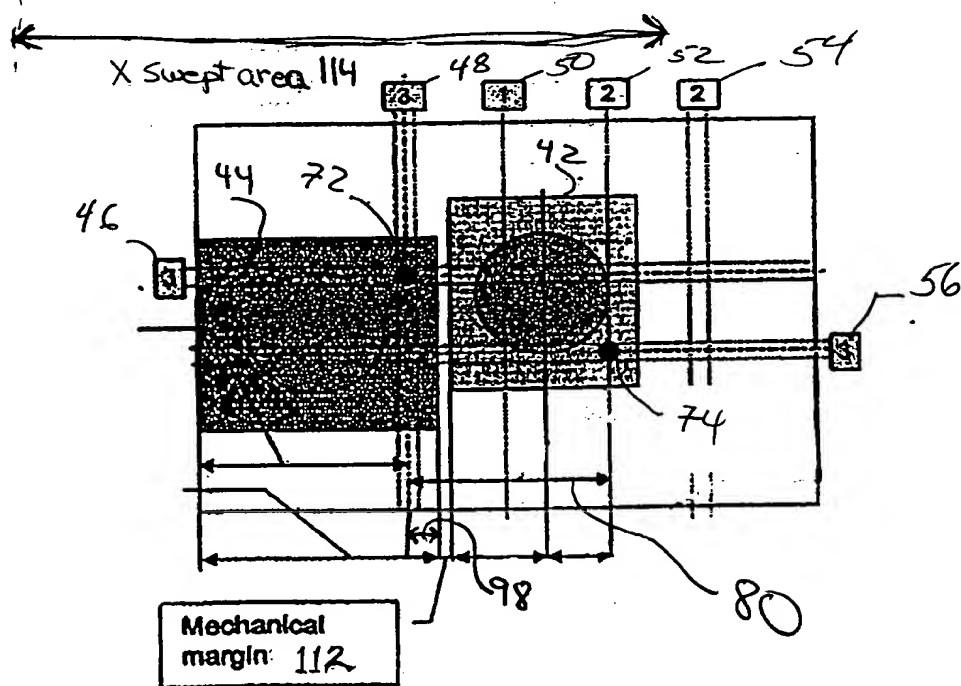
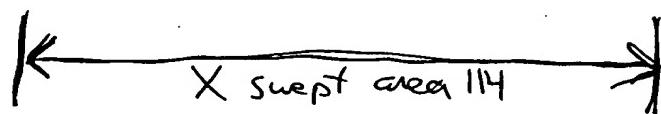


FIG. 9



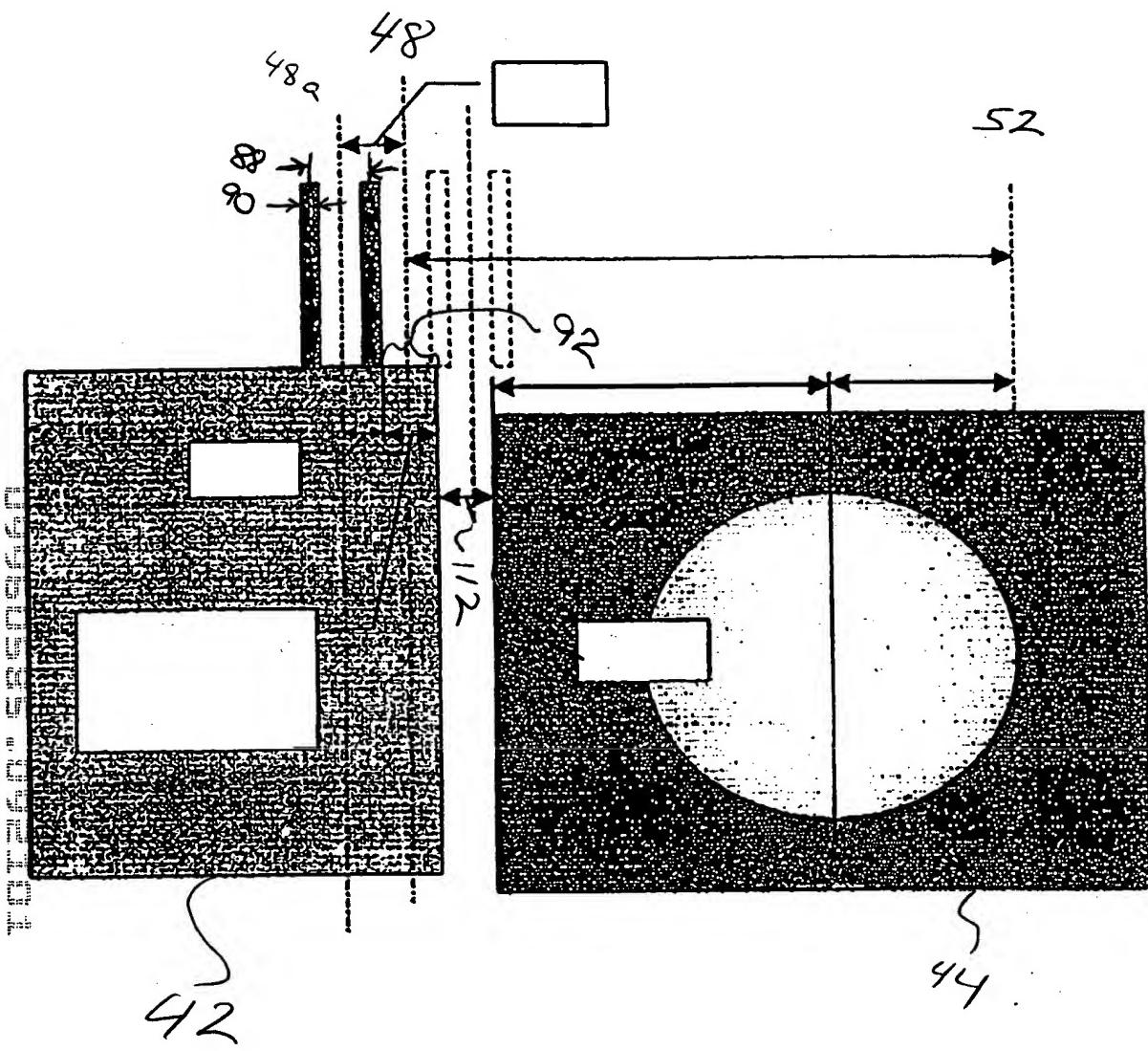
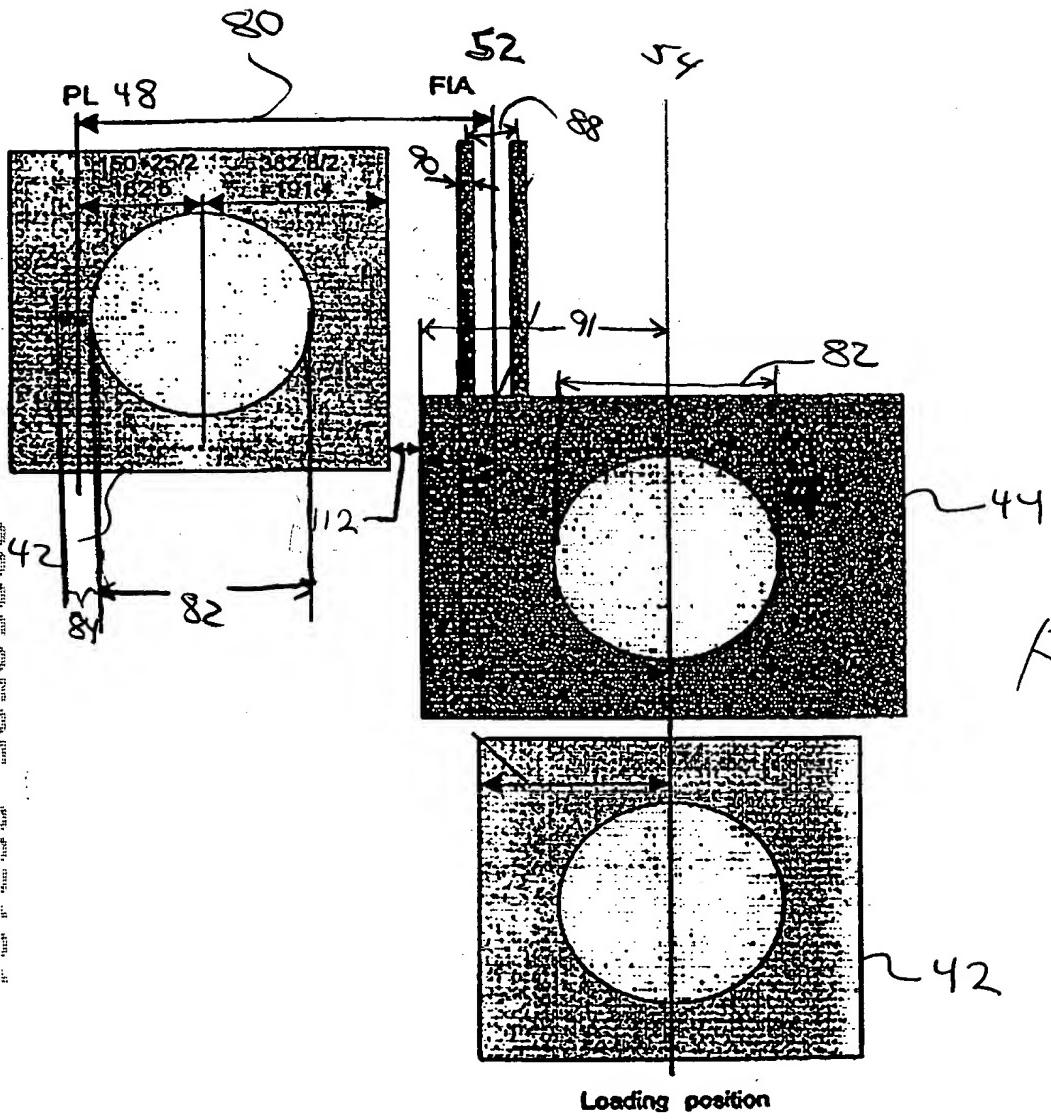
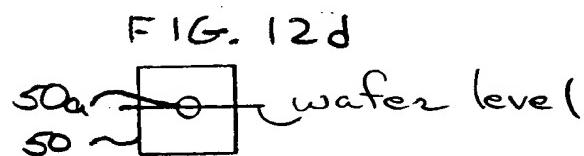
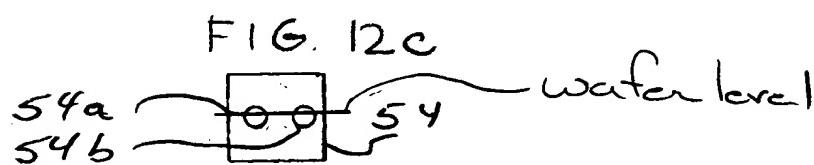
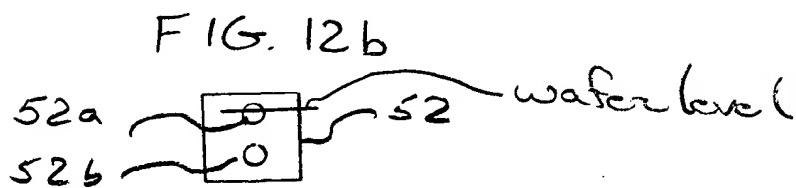
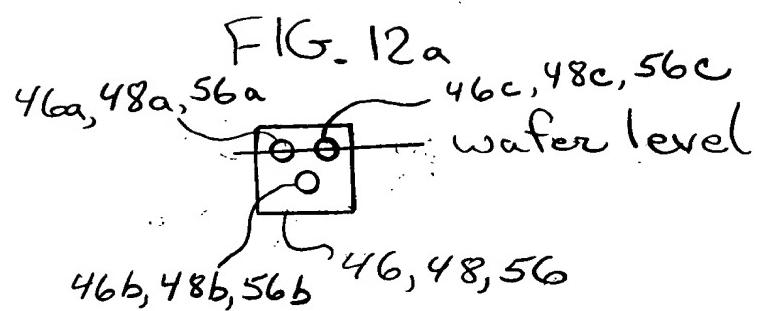


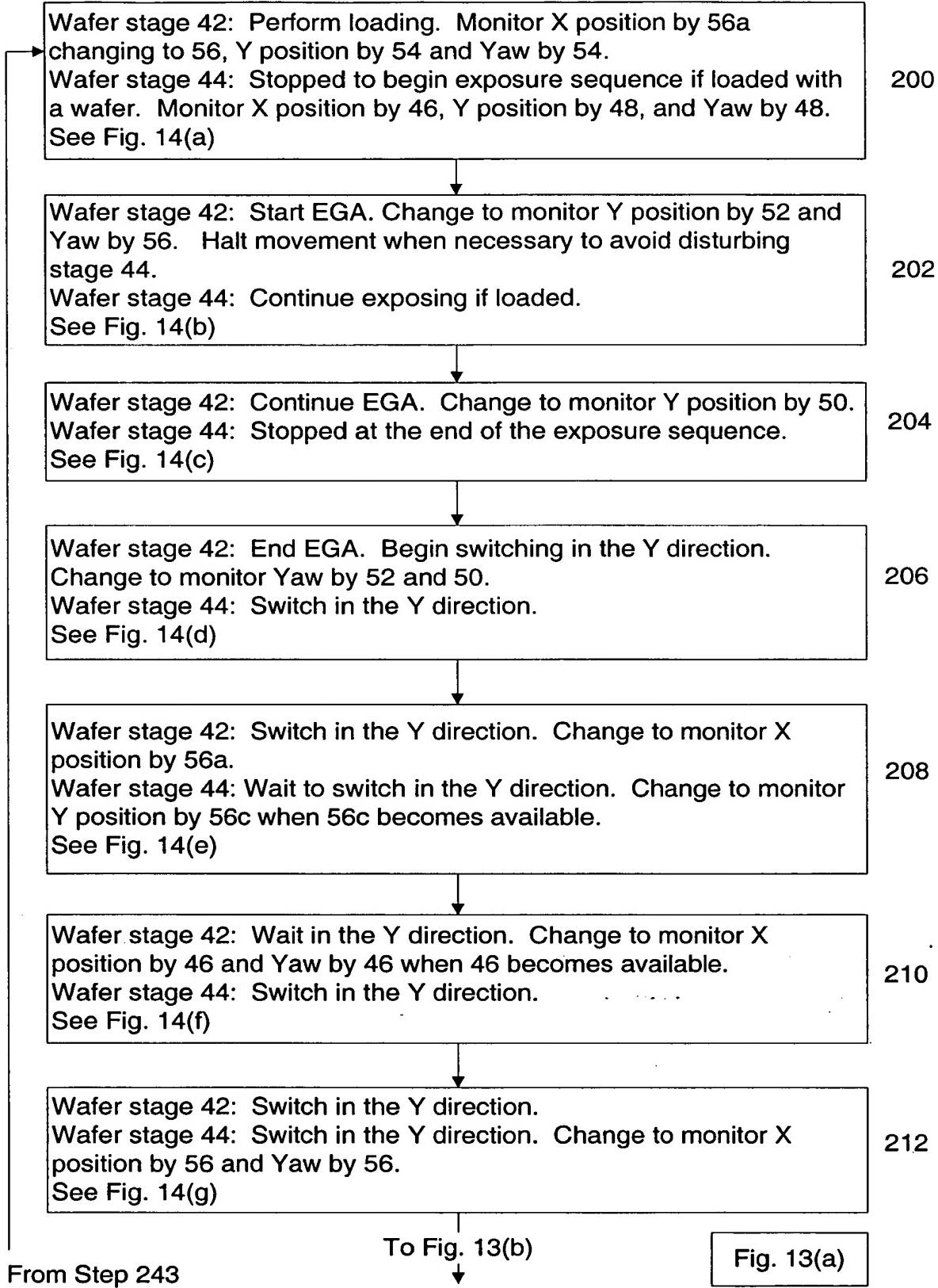
FIG. 10

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To Fig. 13(a)
and step 200

Wafer stage 42: Switch in the X direction. Change to monitor Y position by 48c.

Wafer stage 44: Wait for stage 42 to finish moving. Change to monitor Y position by 48a.

See Fig. 14(h)

214

Wafer stage 42: Wait for stage 44 to finish moving.

Wafer stage 44: Switch in the X direction. Change to monitor Y position by 52.

See Fig. 14(i)

216

Wafer stage 42: Start exposure sequence. Change to monitor Y position by 48.

Wafer stage 44: Switch in the X direction. Change to monitor Y position by 54.

See Fig. 14(j)

218

Wafer stage 42: Start exposure sequence.

Wafer stage 44: Load the wafer.

See Fig. 3

220

Wafer stage 42: Continue exposure sequence.

Wafer stage 44: Continue loading. Change to monitor Y position by 52.

See Fig. 14(l)

222

Wafer stage 42: Continue exposure sequence.

Wafer stage 44: Perform EGA.

See Fig. 14(m)

224

Wafer stage 42: End exposure sequence.

Wafer stage 44: Continue EGA.

See Fig. 14(n)

226

Wafer stage 42: Stop in the safety position and wait for stage 44 to finish EGA.

Wafer stage 44: End EGA.

See Fig. 14(o)

228

To Fig. 13(c)

Fig. 13(b)

0
0
0
0
0
0
0
0
0
0
0
0
0
0

To Fig. 13(a)
and step 200

From Fig. 13(b) and step 228

Wafer stage 42: Stop in the safety position.
Wafer stage 44: Switch in the X direction.
See Fig. 14(p)

230

Wafer stage 42: Switch in the X direction. Change to monitor Y position by 50.
Wafer stage 44: Wait for 48a to become available to control Y position. Resume switching in the X direction.
See Fig. 14(q)

232

Wafer stage 42: Continue switching in the X direction.
Wafer stage 44: Wait in the switch X/wait position. Change to monitor Y position by 48a.
See Fig. 14(r)

234

Wafer stage 42: Continue switching in the X direction. Change to monitor Y position by 52.
Wafer stage 44: Wait in the switch X/wait position. Change to monitor Y position by 48 and Yaw by 48.
See Fig. 14(s)

236

Wafer stage 42: Continue switching in the X direction. Change to monitor Y position by 54 and Yaw by 54.
Wafer stage 44: Wait in the switch X/wait position.
See Fig. 14(t)

238

Wafer stage 42: Switch in the Y direction. Change to monitor X position by 56a.
Wafer stage 44: Switch in the Y direction. Change to monitor X position by 56c.
See Fig. 14(u)

240

To Fig. 13(d)

FIG 13(c)

To Fig. 13(a)
and step 200

From Fig. 13(c) and step 240

Wafer stage 42: Wait in the switchY/wait position then move to the loading position.
Wafer stage 44: Continue switching in the Y direction and attain the position to begin the exposure sequence. Change to monitor X position by 46.
See Fig. 14(v)

242

Yes

Continue to process more wafers ?

243

No

Wafer stage 42: Unload but do not reload. Change to monitor X position by 56.
Wafer stage 44: Start exposure sequence.
See Fig. 14(a)

244

Wafer stage 42: Move through the EGA movements without performing EGA, halting to avoid disturbing stage 44. Change to monitor Y position by 52 and Yaw by 56.
Wafer stage 44: Continue the exposure sequence.
See Fig. 14(b)

246

Wafer stage 42: Change to monitor Y position by 50.
Wafer stage 44: Stop at the end of the exposure sequence.
See Fig. 14(c)

248

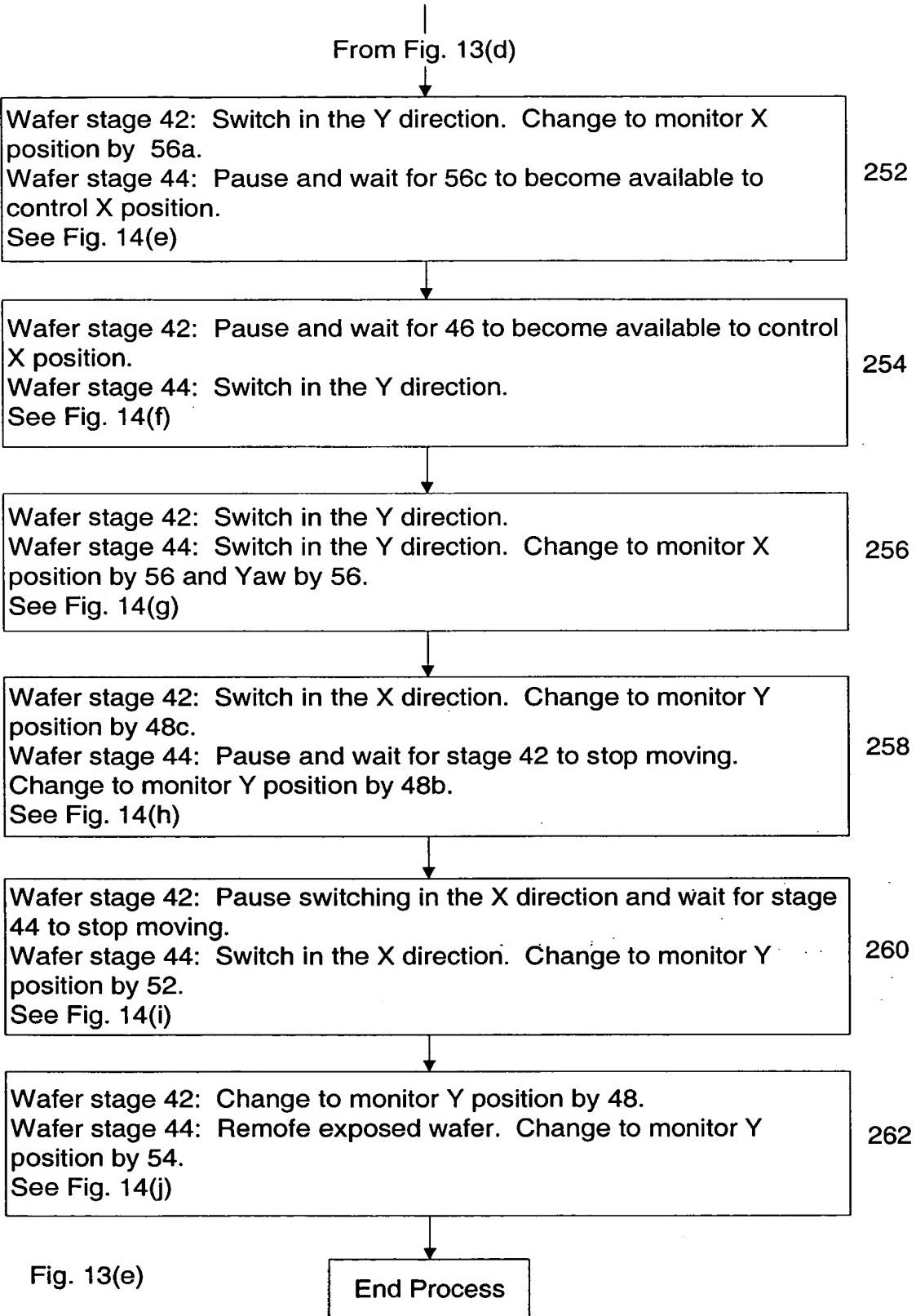
Wafer stage 42: Switch in the Y direction. Change to monitor Yaw by 52 and 50.
Wafer stage 44: Switch in the Y direction.
See Fig. 14(d)

250

To Fig. 13(e)

Fig. 13(d)

0 0 0 0 0 0 0 0 0 0 0 0 0 0 0 0



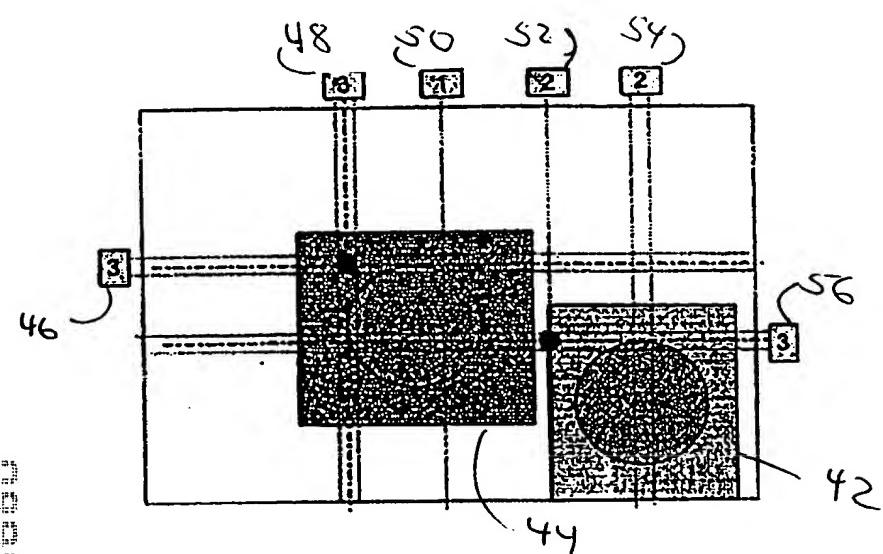


FIG.

14(a)

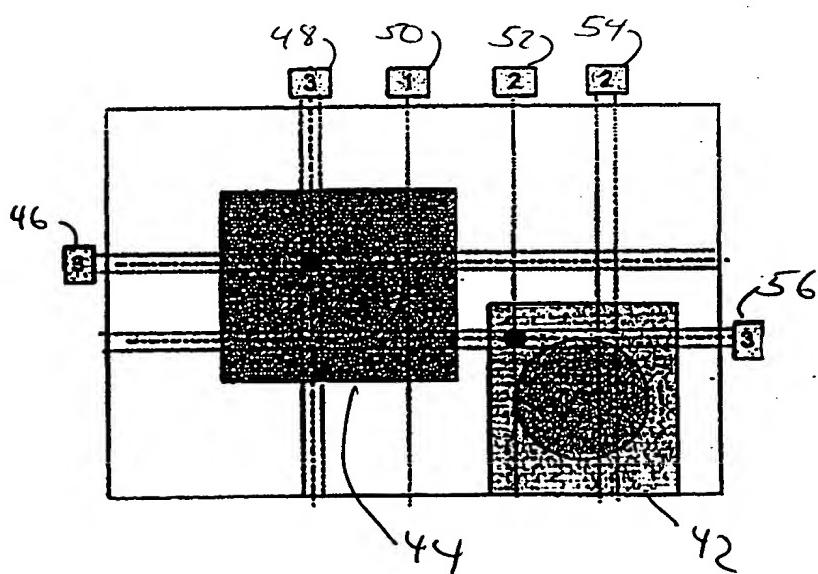


FIG.

14(b)

0 0 0 0 0 0 0 0 0 0 0 0 0 0 0

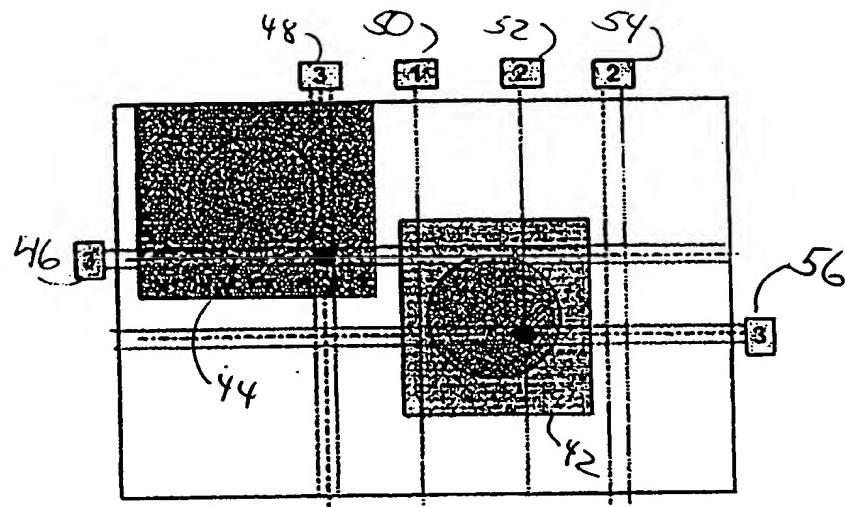


FIG.
14(c)

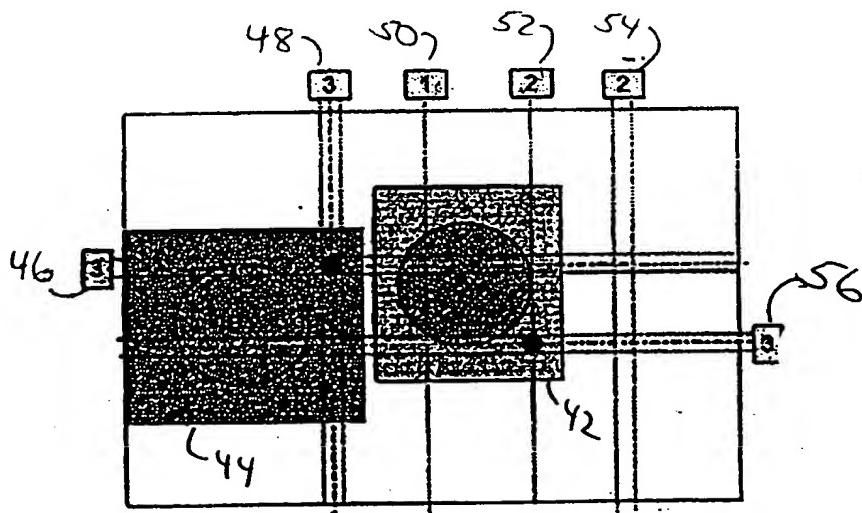


FIG.
14(d)

03360635 032103

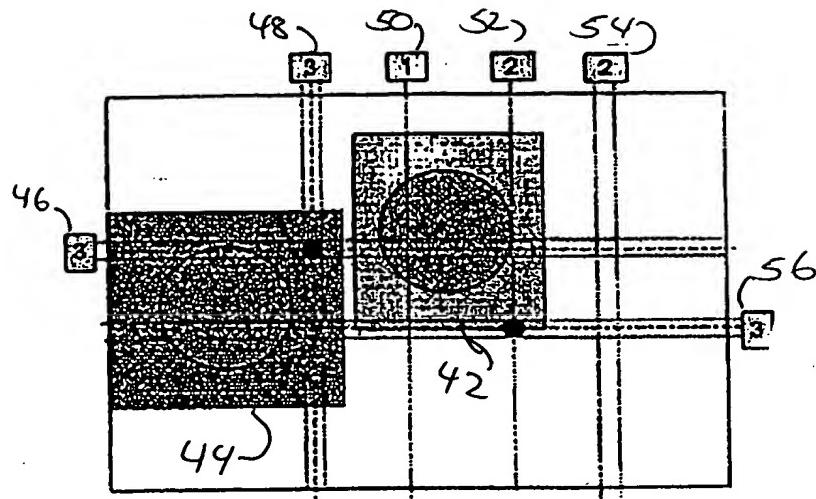


FIG.
14(e)

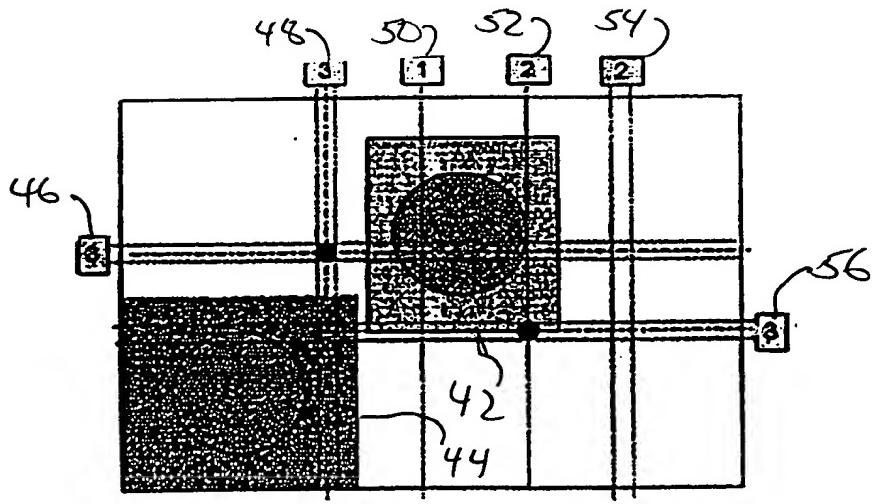


FIG.
14(f)

020560555 - 020100

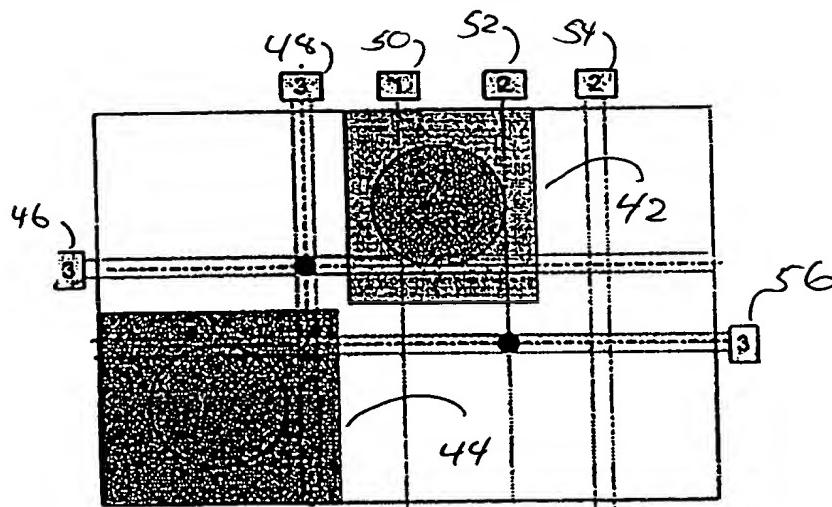


FIG.
14(g)

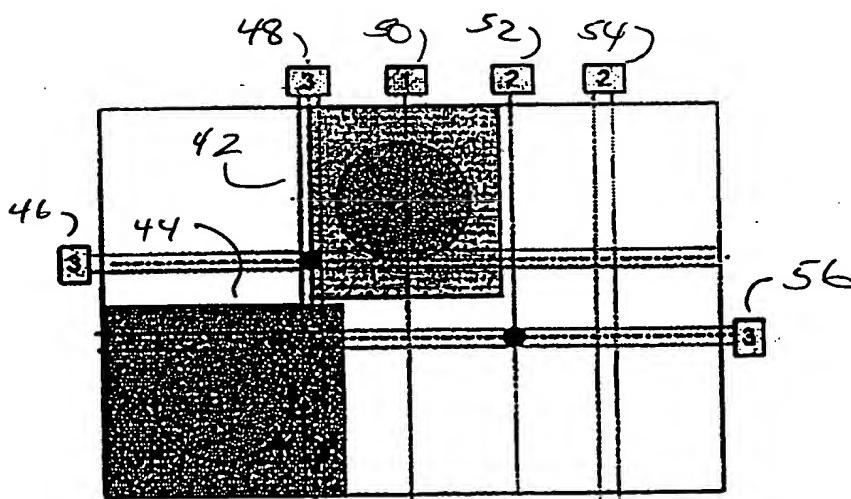


FIG.
14(h)

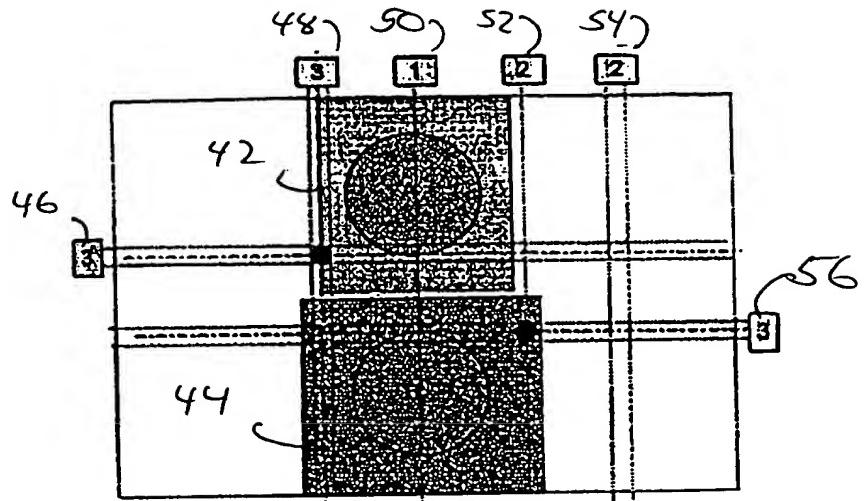


FIG.
14(c)

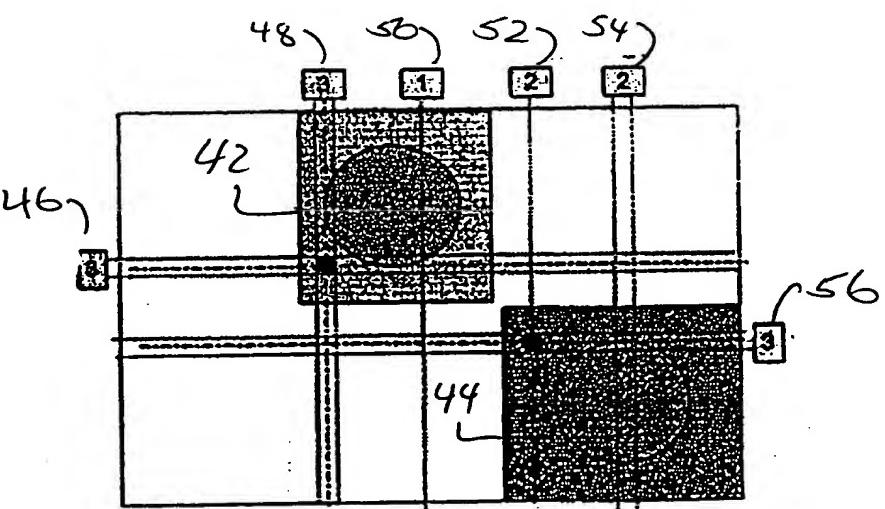
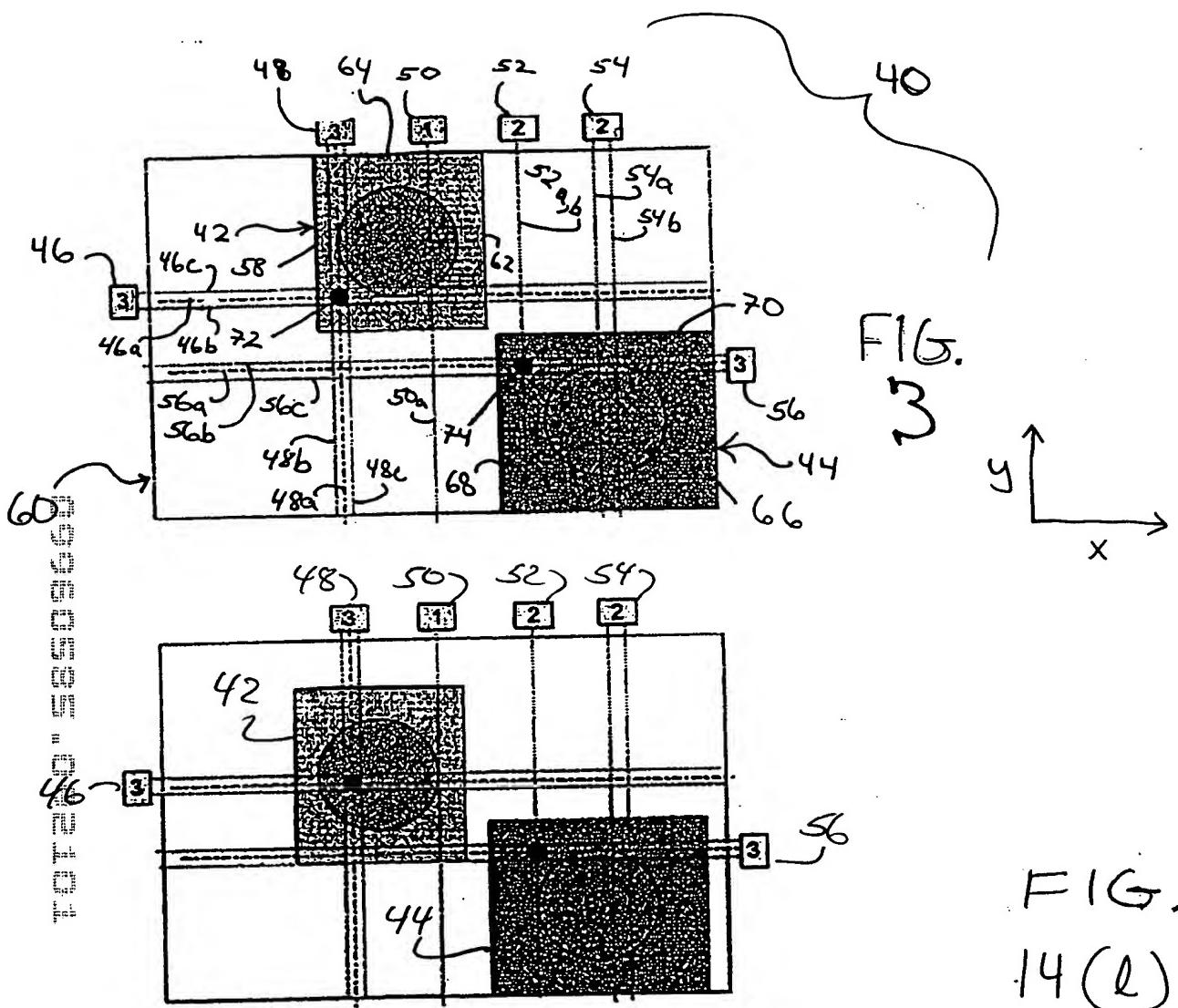


FIG.
14(j)



0000000000000000

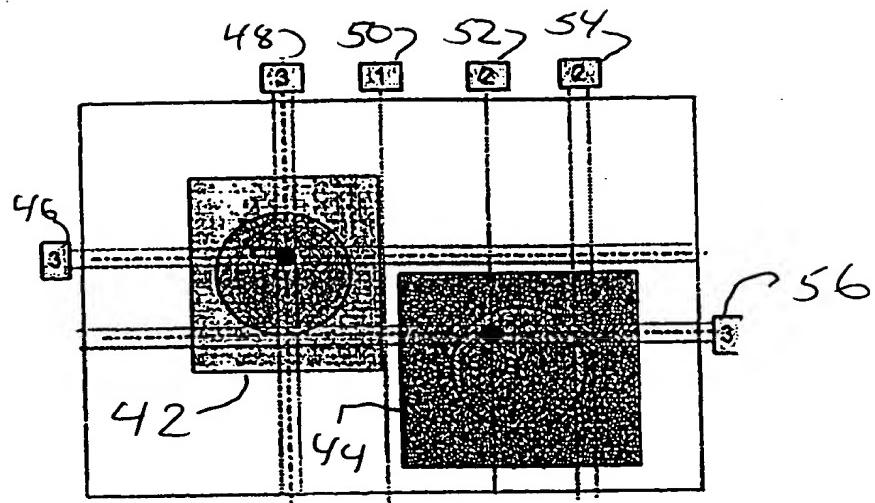


FIG.
14(m)

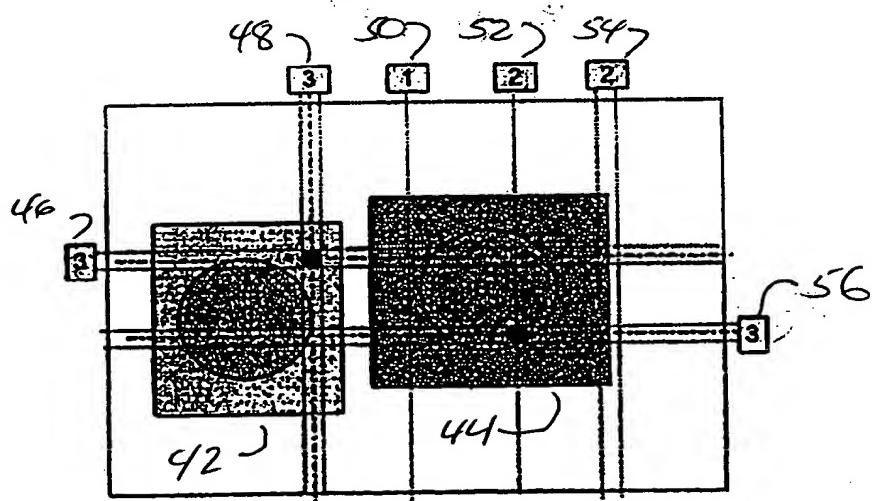


FIG.
14(n)

0 9 0 0 0 0 0 0 0 0 0 0 0 0 0 0

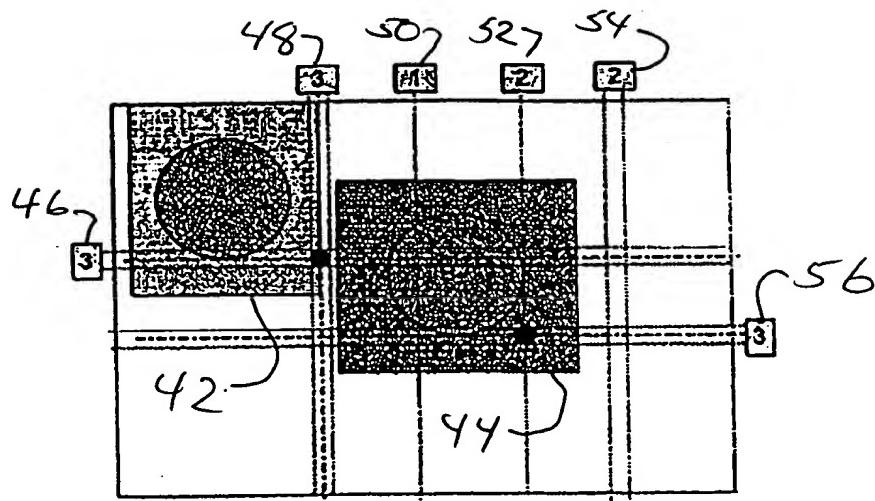


FIG.
14(o)

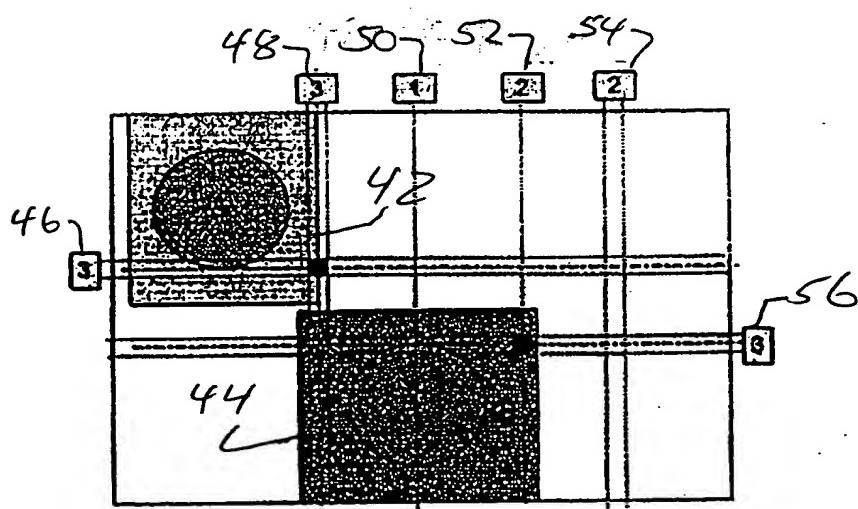


FIG.
14(p)

00960553-0000-10

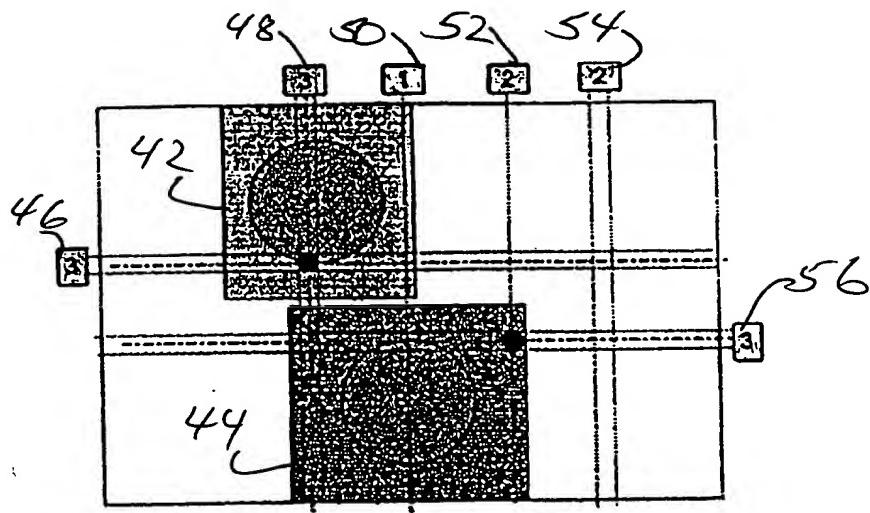


FIG.
14(g)

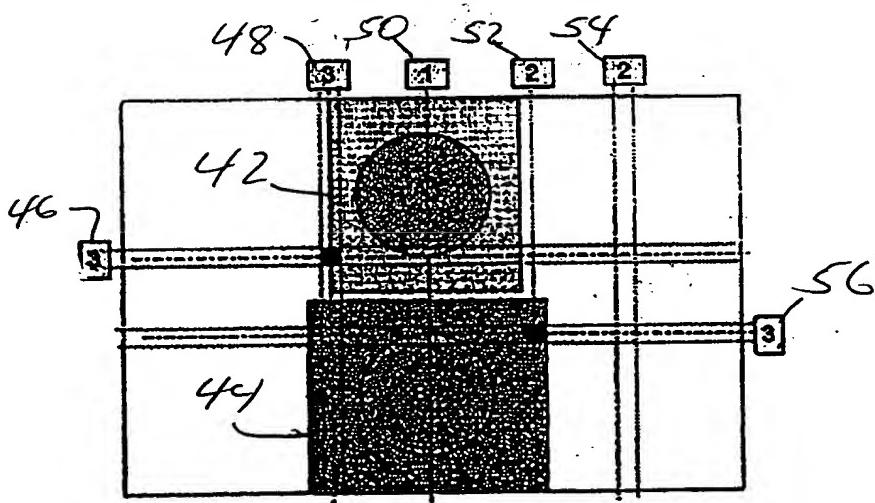


FIG.
14(r)

09963325 0922100

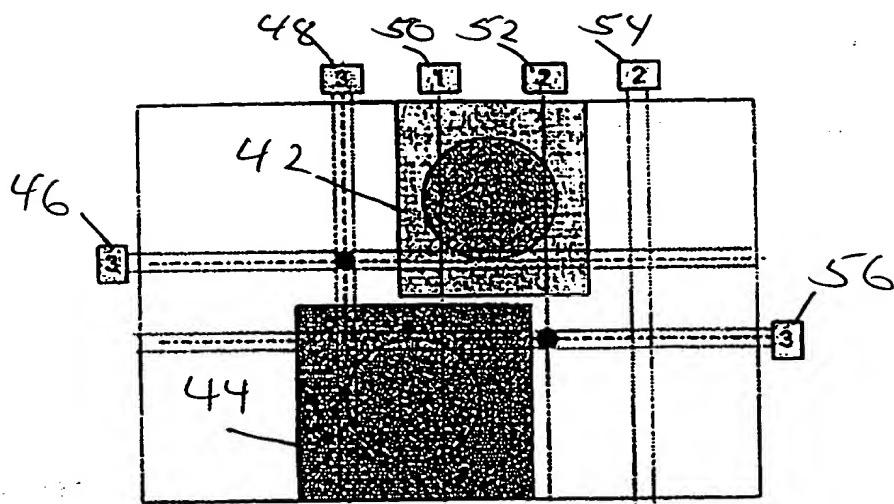


FIG.
14(S)

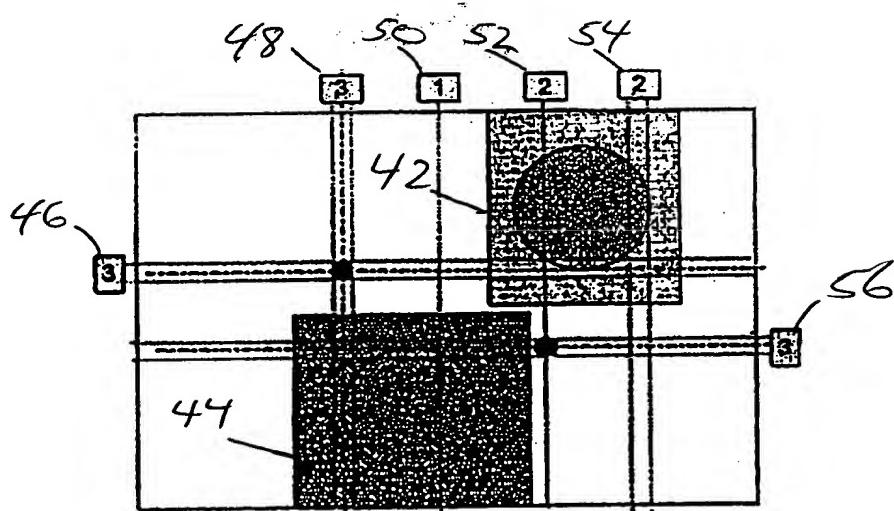


FIG.
14(T)

000000000000000000000000

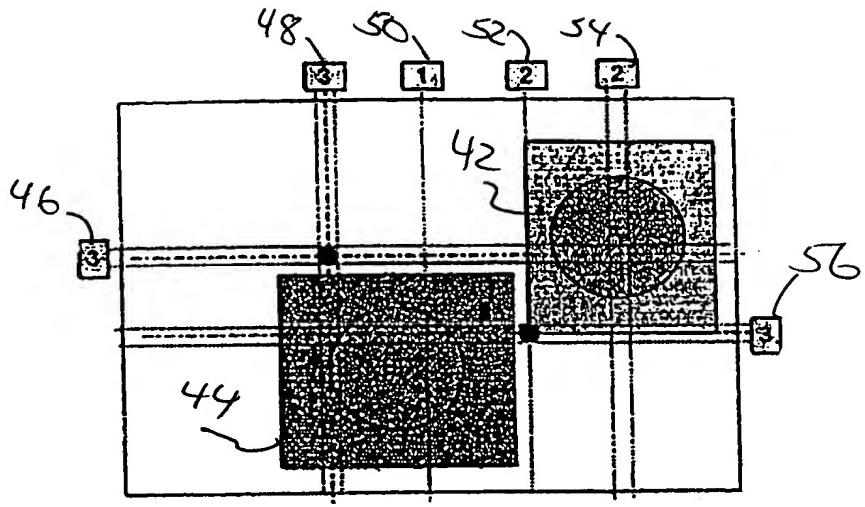


FIG.
14(u)

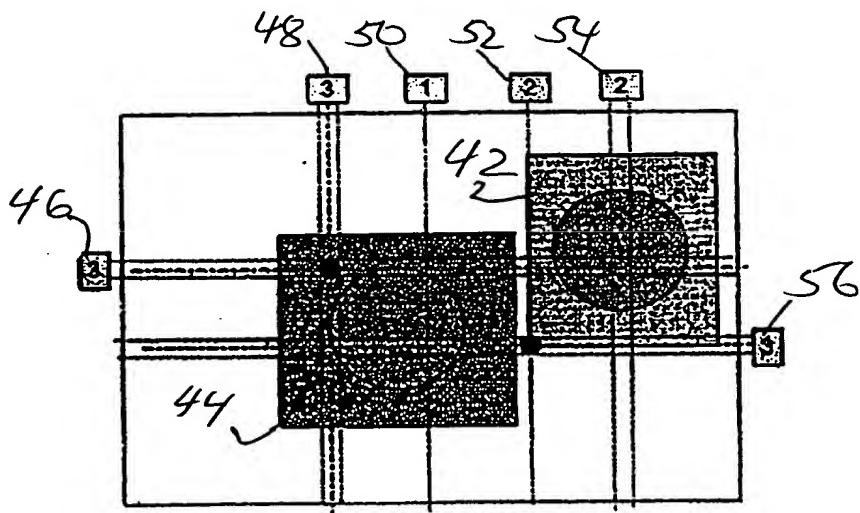


FIG.
14(v)